



GT NanoMécanique – 16/10/2018 Montpellier

Mesure par AFM de la raideur de contact sur matériaux élastiques rigides : De quoi parle-t-on ?

Quelles sont les domaines de validité et les limites (actuelles) ?

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EQUIPE BOIS

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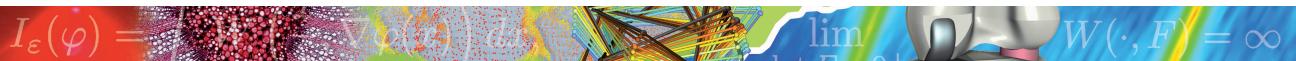
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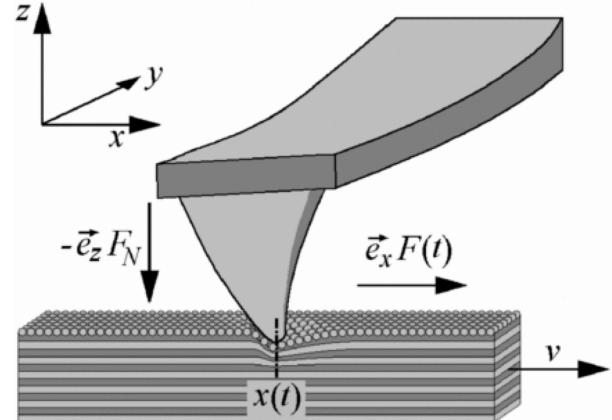
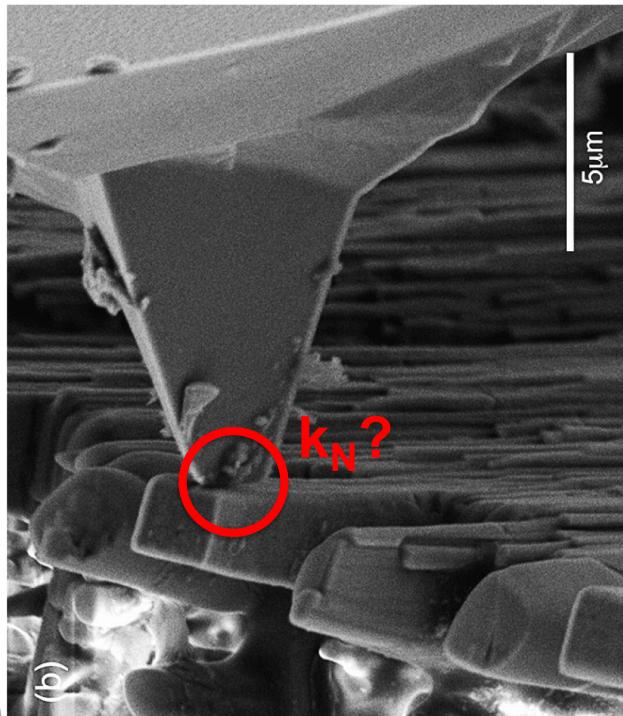
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 - Dynamique du levier et effet de la raideur latérale
- Préparation de la surface et calibrations

$$I_\varepsilon(\varphi) = \int_{\Omega} \left(\frac{1}{2} |\nabla \varphi|^2 + V(\varphi) \right) dx, \quad \lim_{|\varphi| \rightarrow \infty} W(\cdot, F) = \infty$$

Contact mechanics

Bone micromechanics using in situ AFM in SEM



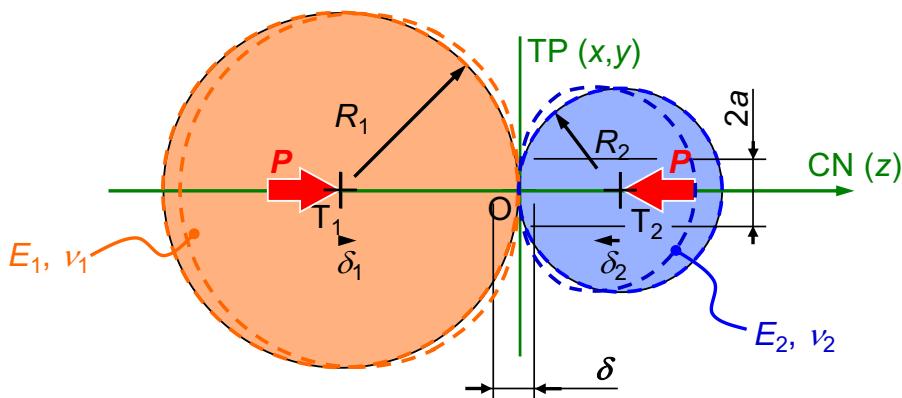
[<http://www.physik.uni-bielefeld.de>]

[Jimenez-Palomar et al., J. Mech. Beh. Bio. Mat., 2011]

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$$I_\varepsilon(\varphi) = \int_{\Omega} \left(\frac{1}{2} |\nabla \varphi|^2 + V(\varphi) \right) dx, \quad \lim_{|\varphi| \rightarrow \infty} W(\cdot, F) = \infty$$

Contact mechanics



- Aims at finding the relationship between:

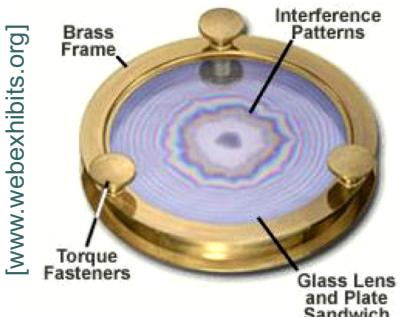
- the load P and the relative displacement δ of the two bodies (far away from the contact)
- the load P and the shape and size a of the contact area
- the load P and the stress fields in each bodies

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Contact mechanics

- Hertz's theory (1882 Ger. → 1896 Eng.)

- ↳ Elastic deformation of two glass lenses in contact



- ↳ Assumptions:

- Surfaces are continuous and **non-conforming** (i.e., $R_1 \neq -R_2$) $\rightarrow a \ll R$
- Strains are small: $a \ll R$
- Linear elastic isotropic and homogeneous materials
- Friction is neglected

- ↳ Each solid is considered as an elastic half-space (plane) loaded over a small *elliptical* region of its plane surface

[K.L. Johnson, Contact Mechanics, Cambridge University Press, 2001]

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Contact mechanics

- Hertz's theory (1882)

- ↳ Results: macroscopic relationship

$$a = \left(\frac{3RP}{4E^*} \right)^{1/3}$$

$$p_0 = \left(\frac{6PE^{*2}}{\pi^3 R^2} \right)^{1/3}$$

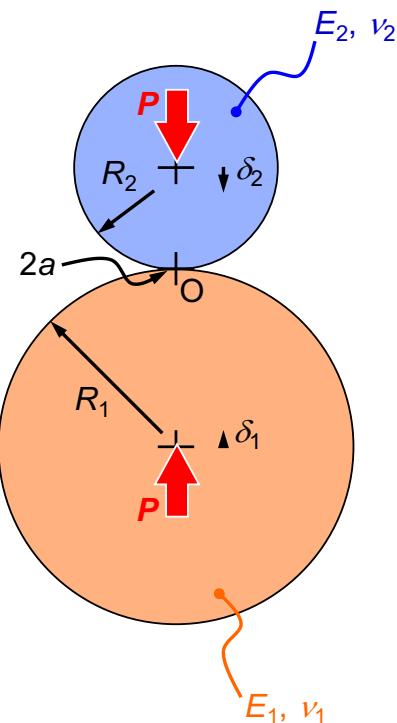
$$\delta = \delta_1 + \delta_2 = \left(\frac{9P^2}{16RE^{*2}} \right)^{1/3} = \frac{a^2}{R} \quad \left| \begin{array}{l} P = \frac{4}{3} E^* \sqrt{R} \delta^{3/2} \\ P = \frac{4}{3} E^* \frac{a^3}{R} \end{array} \right.$$

$$\Rightarrow k_N = \frac{\partial P}{\partial \delta} = (6E^{*2}RP)^{1/3} = 2E^* \sqrt{R\delta} = 2E^*a$$

$$0 \leq k_t \leq \frac{2-\nu}{2(1-\nu)}$$

$$\frac{1}{E^*} = \frac{1-\nu_1^2}{E_1} + \frac{1-\nu_2^2}{E_2}$$

$$\frac{1}{R} = \frac{1}{R_1} + \frac{1}{R_2}$$



Contact modulus

Plane-stress modulus

Visco-elasticity...

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$$I_\varepsilon(\varphi) = \int_{\Omega} \left(\frac{1}{2} |\nabla \varphi|^2 - V(\varphi) \right) dx, \quad W(\cdot, F) = \infty$$

Contact mechanics

- Hertz's theory (1882)

- ↳ Examples in the case of Si-AFM probe ($R_2=10\text{nm}$, $E_2 \approx 150\text{GPa}$) in contact with the planar surface ($R_1 \rightarrow \infty$) of different materials [www.ntmdt.com]

Material and its Young's modulus	Contact area radius a , nm	Penetration due to deformation h , nm	Contact pressure p , GPa
Elastomer, $E = 0.65\text{GPa}$	3.74	8.04	1.04
PS, $E = 1\text{GPa}$	3.24	6.98	1.05
Copper, $E = 120\text{GPa}$	0.79	1.7	0.062
Tungsten, $E = 400\text{GPa}$	0.68	1.46	0.046
Diamond, $E = 1000\text{GPa}$	0.64	1.38	0.041
at loading force F , nN			
	5	50	5
			50

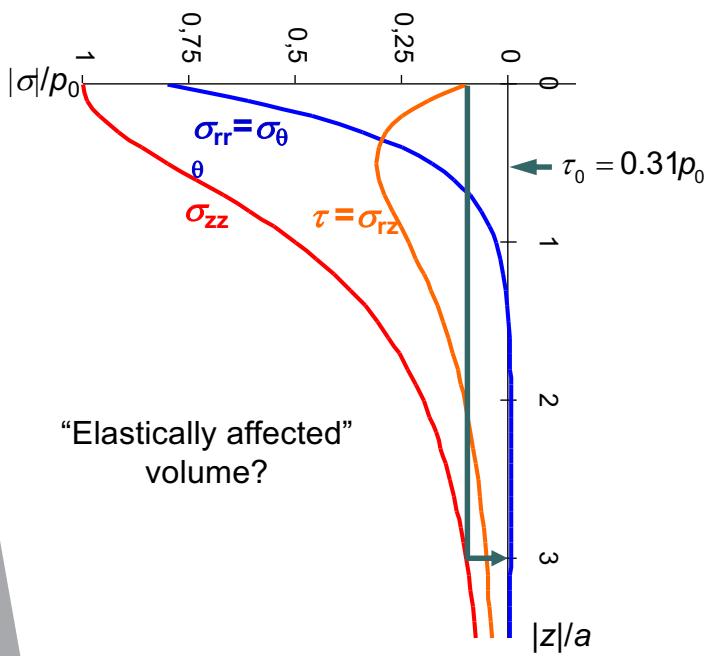
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$$I_\varepsilon(\varphi) = \int_{\Omega} \left(\frac{1}{2} |\nabla \varphi|^2 - V(\varphi) \right) dx, \quad W(\cdot, F) = \infty$$

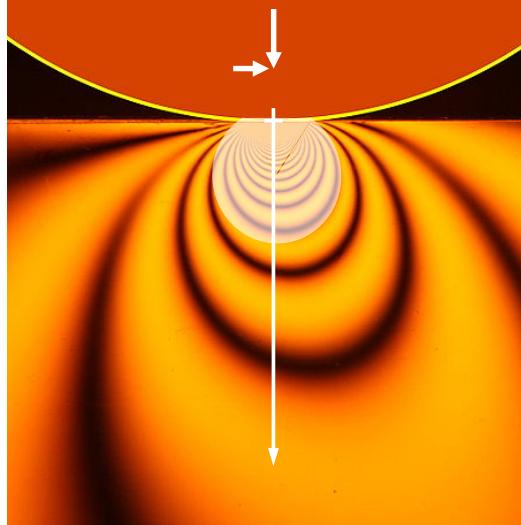
Contact mechanics

- Hertz's theory (1882)

- ↳ Results: stress field



“Stress field” during a combined normal and tangential load contact made visible by photoelasticity



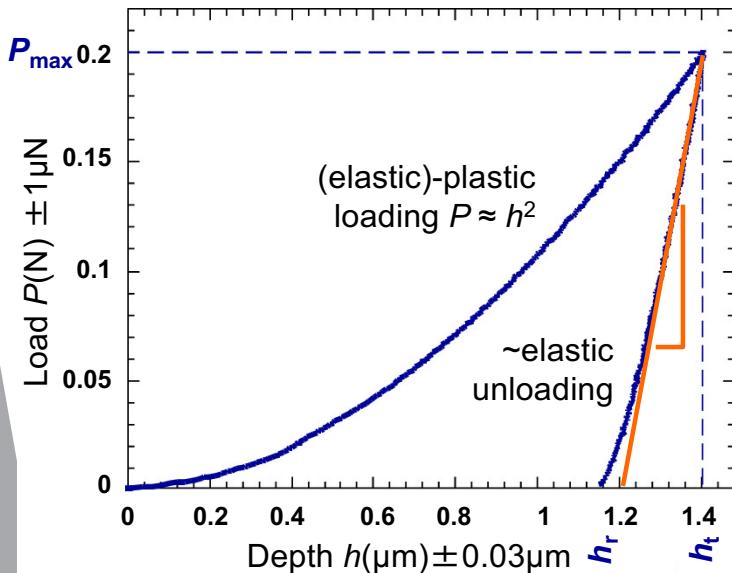
[www.wikimedia.org]

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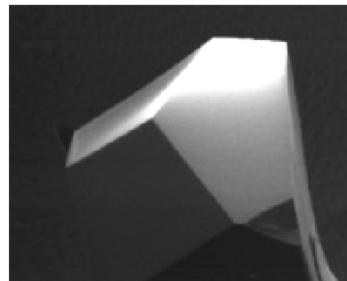
Contact mechanics

- (Depth-sensing) Nanoindentation

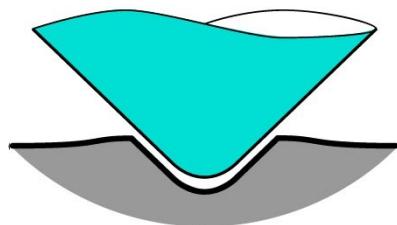
- The depth of penetration h ($\delta!$) is measured during load application mainly with a Berkovich indenter (3-sided pyramid)



Nanoindentation curve on electrodeposited Ni



[www.microstartech.com]



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Contact mechanics

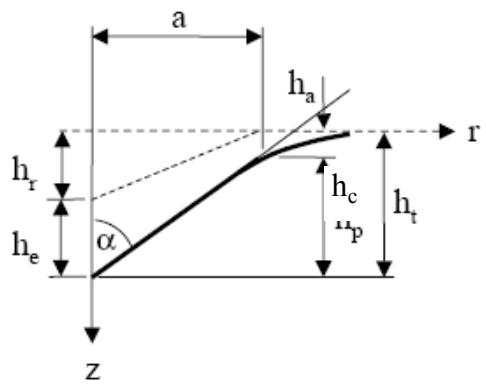
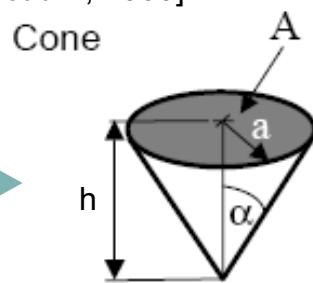
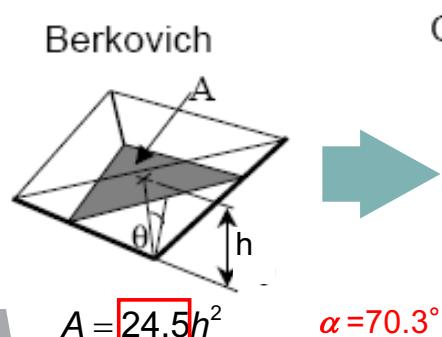
- (Depth-sensing) Nanoindentation

$$E^* = \frac{\sqrt{\pi}}{2} \frac{dP}{dh} \frac{1}{\sqrt{A_c}}$$

With E^* or M reduced/contact/indentation modulus
 $\frac{1}{E^*} = \frac{1-\nu_i^2}{E_i} + \frac{1-\nu^2}{E}$ for linear **ISOTROPIC** material

- Case of the Berkovich indenter

[A.C. Fischer-Cripps, Vacuum, 2000]



$$h_c = h_t - \varepsilon P \left(\frac{dP}{dh} \right)^{-1} \quad \text{with } \varepsilon = \begin{cases} \frac{2(\pi-2)}{\pi} \\ 0.75 \end{cases}$$

cone

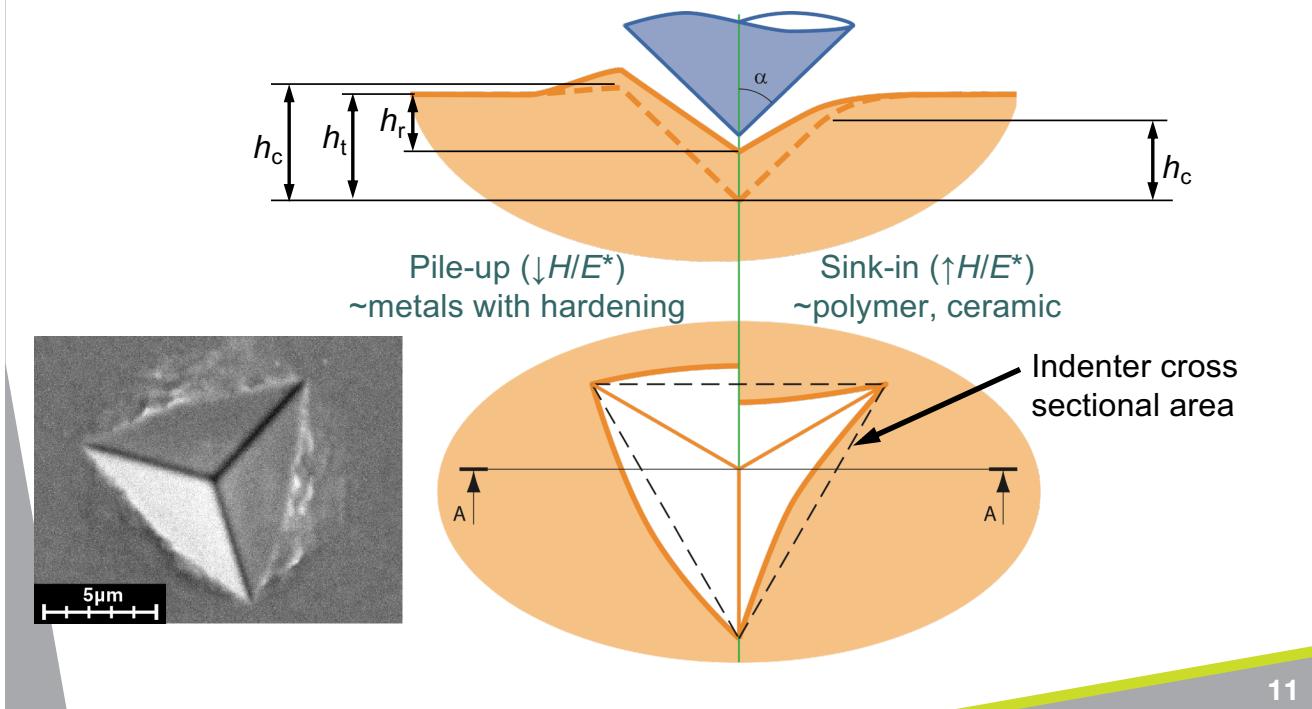
Berkovich

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$$I_\varepsilon(\varphi) = \frac{1}{2} \int_{\Omega} \left(|\nabla \varphi|^2 + V(\varphi) \right) dx \quad \lim_{\varepsilon \rightarrow 0^+} I_\varepsilon(\varphi) = W(\cdot, F) = \infty$$

Contact mechanics

- (Depth-sensing) Nanoindentation

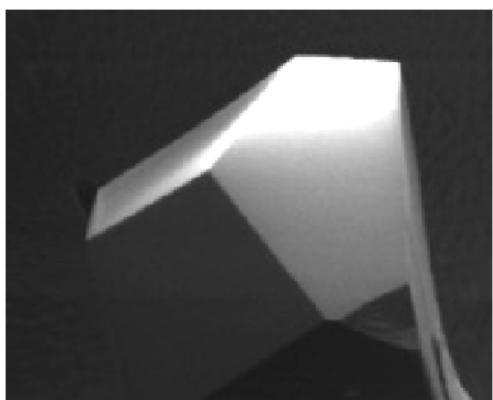


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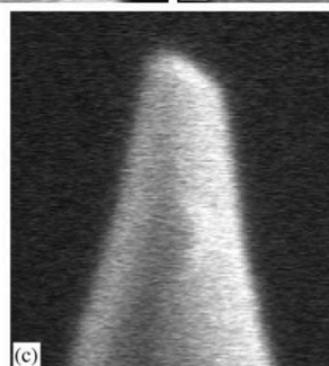
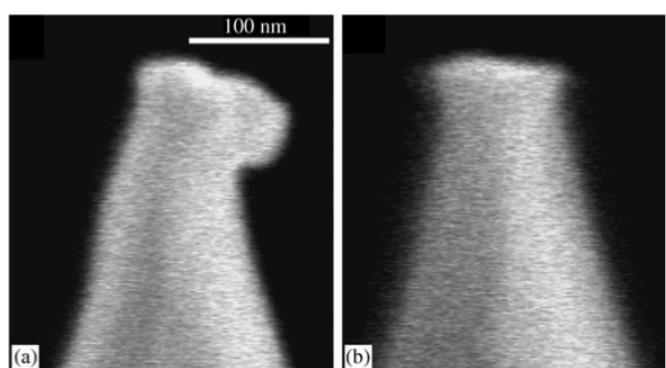
$$I_\varepsilon(\varphi) = \frac{1}{2} \int_{\Omega} \left(|\nabla \varphi|^2 + V(\varphi) \right) dx \quad \lim_{\varepsilon \rightarrow 0^+} I_\varepsilon(\varphi) = W(\cdot, F) = \infty$$

Contact mechanics – NI vs AFM

Tip deformation on (very) stiff material and high load (set-point) !



[www.microstartech.com]



NEAR SURFACE measurements
→ sample surface preparation!!!

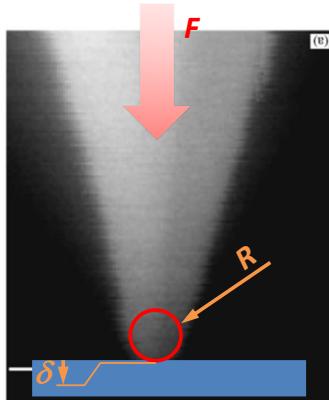
[Kopycinska-Müller et al, Ultramicroscopy, 2006; Nanotechnology, 2016]

$$I_\varepsilon(\varphi) = \dots$$

$$\lim$$

$$W(\cdot, F) = \infty$$

Contact mechanics – NI vs AFM



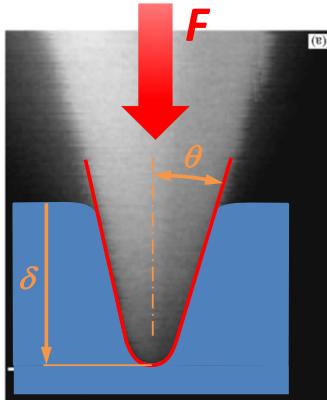
✓ Hertz (1885)

$$F = \frac{4}{3} M R_{eq}^{1/2} \delta^{3/2}$$

$$k_N = (6 M^2 R_{eq} F)^{1/3}$$

$\delta \ll R$

Non conforming



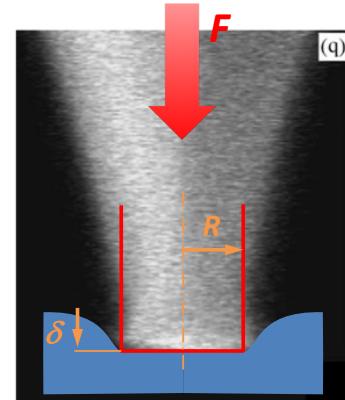
✓ Sneddon (1965)

$$F = \frac{2}{\pi} M \tan \theta \delta^2$$

$$k_N = \left(\frac{32}{\pi^3} M \tan \theta F \right)^{1/2}$$

$\delta \approx R??!!$

$E^*_{sample} \ll E^*_{tip}$



✓ Flat punch (??)

$$F = 2 M R S$$

$$k_N = 2 M R$$

M: Reduced/contact modulus

$$\frac{1}{M} = \frac{1 - \nu_{Tip}^2}{E_{Tip}} + \frac{1 - \nu_{Sample}^2}{E_{Sample}}$$

[Kopycinska-Müller et al, Ultramicroscopy, 2006]

! Non conforming

$\delta \approx R??!!$

LINEAR ELASTIC HOMOGENEOUS and ISOTROPIC materials

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$$I_\varepsilon(\varphi) = \dots$$

$$\lim$$

$$W(\cdot, F) = \infty$$

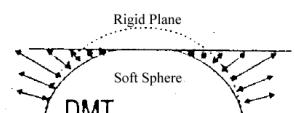
Contact mechanics + adhesion (capillary, Van der Waals, ...)

✓ DMT Model: $\left\{ \begin{array}{l} \text{Adhesive model} \\ \text{Hertz model + offset of applied load} \end{array} \right.$

$$k_{N_{DMT}} = \left(6 M^2 R \left(F + F_{ad_{DMT}} \right) \right)^{1/3}$$

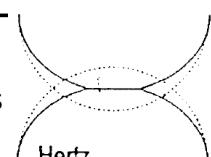
$$\text{Adhesion force } F_{ad_{DMT}} = 2 \pi R w_{ad}$$

Used for hard samples, low adhesion force and low tip radius R



✓ JKR Method: $\left\{ \begin{array}{l} \text{Adhesive model} \\ \text{Evaluation of the energy of adhesion between two solids} \end{array} \right.$

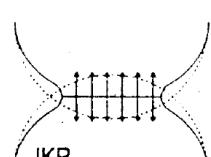
Hertz's theory is no longer valid: no direct relation between F and δ



$$k_{N_{JKR}} = 2 M a_{JKR} \frac{1 - \frac{1}{2} \left(\frac{a_{0_{JKR}}}{a_{JKR}} \right)^{3/2}}{1 - \frac{1}{6} \left(\frac{a_{0_{JKR}}}{a_{JKR}} \right)^{3/2}}$$

with

$$\left\{ \begin{array}{l} a_{JKR} = \left[\frac{3R}{4M} \left(\sqrt{F_{ad_{JKR}}} + \sqrt{F_{ad_{JKR}} + F} \right)^2 \right]^{1/3} \\ a_{0_{JKR}} = \left[\frac{3RF_{ad_{JKR}}}{M} \right]^{1/3} \\ F_{ad_{JKR}} = \frac{3}{2} \pi R w_{ad} \end{array} \right.$$



At pull-off $a \neq 0$ and $F = -F_{ad}$

[R.M. Overney]

→ Adapted to soft samples, high adhesion force and high tip radius R

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Contact mechanics - Anisotropy

- ⌚ Extension of the theory to the case of anisotropic solids → Green's function?
[Willis, J. Mech. Phys. Solids, 1966; Vlassak et al., J. Mech. Phys. Solids, 1994/2003; Swadener et al., Philos. Mag. A, 2002...]

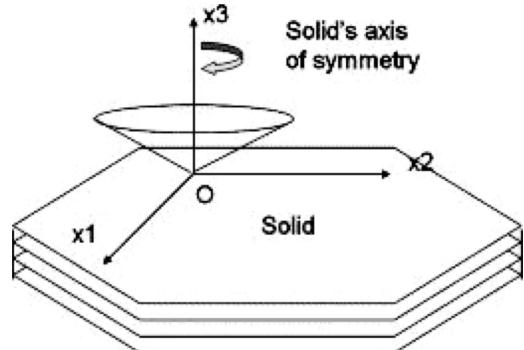
$$\frac{E}{1-\nu^2} = \frac{C_{11}^2 - C_{12}^2}{C_{11}} \rightarrow M$$

$1=2=3$

- ⌚ Closed form solution of M only available in particular case...
→ transversely isotropic // contact surface
[Hanson, J. Appl. Mech., 1992]

$$M_3 = 2 \sqrt{\frac{C_{11}C_{33} - C_{13}^2}{C_{11}}} \left(\frac{1}{C_{44}} + \frac{2}{\sqrt{C_{11}C_{33}} + C_{13}} \right)^{-1}$$

$1=2:$ C_{22} C_{23} $G_{13}=G_{23}$



[Delafargue et al., Int. J. Sol. Struct., 2004]

$k_t = ?$

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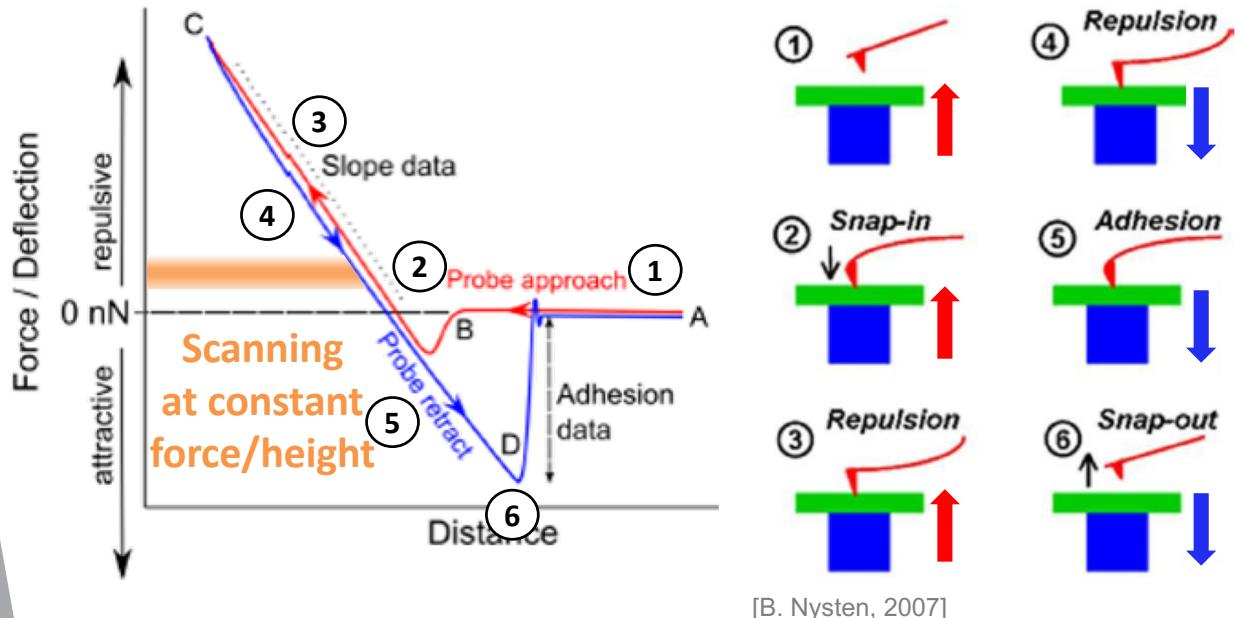
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$$I_\varepsilon(\varphi) = \dots$$

Force-distance curve

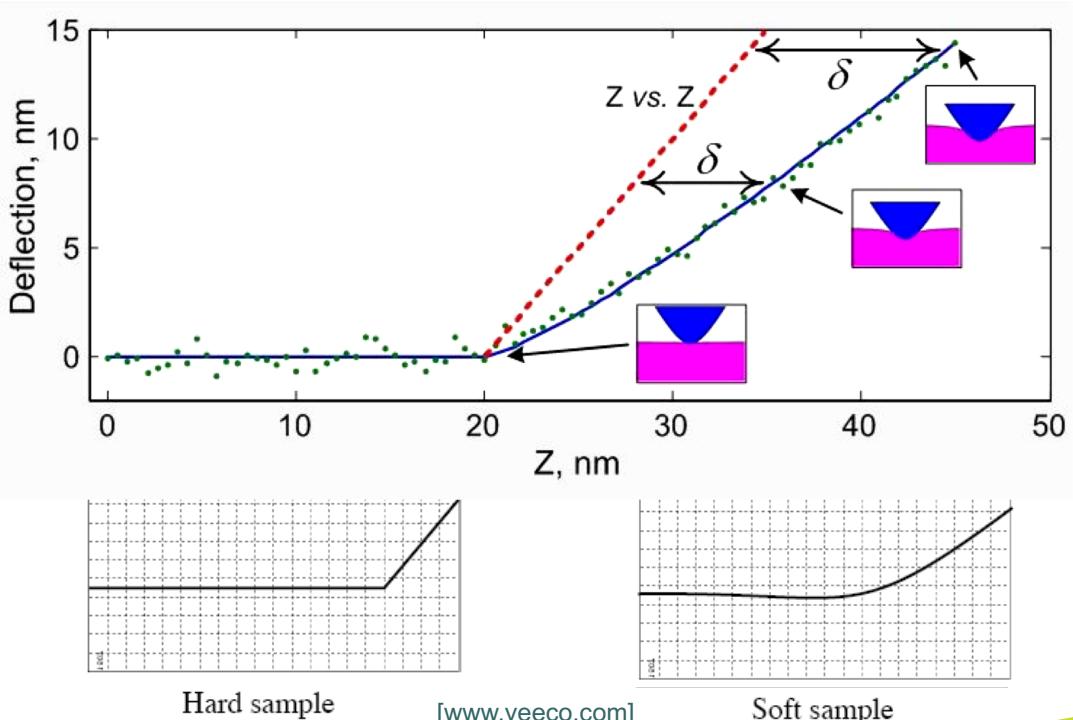


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$$I_\varepsilon(\varphi) = \dots$$

F_d - Indentation

- Decoupling load/displacement



www.chem.duke.edu/~boris/research/elasticity/

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$$I_\varepsilon(\varphi) = \dots$$

Fd - Indentation

- Requirements:

- ↳ Cantilever stiffness

$$\frac{d}{z} = \frac{1}{1 + \frac{k_c}{k_N}} \quad | \quad k_N \gg k_c \rightarrow d = z$$



$$k_N \ll k_c \rightarrow d = 0$$

$$k_N \sim k_c$$

$$k_{N_{DMT}} = \left(6M^2R(F + F_{ad_{DMT}}) \right)^{1/3}$$

with

$$F = k_c d = k_c \chi V_{A-B}$$

- ↳ Calibration of the laser/photodetector
 - ↳ Calibration of the cantilever stiffness
 - ↳ Measurements of the real tip apex shape + **suitable** contact model...
 - ↳ Non-normal load (shear) due to cantilever tilt + tip sliding?
 - ↳ Limited resolution (>100 nm on polymer) due to large tip surface contact area
 - ↳ Mapping (Force-Volume mode) of the elastic properties is very time consuming (256 x 256 points = 18h)
- Force Modulation Mode... PeakForce QNM, QI, etc

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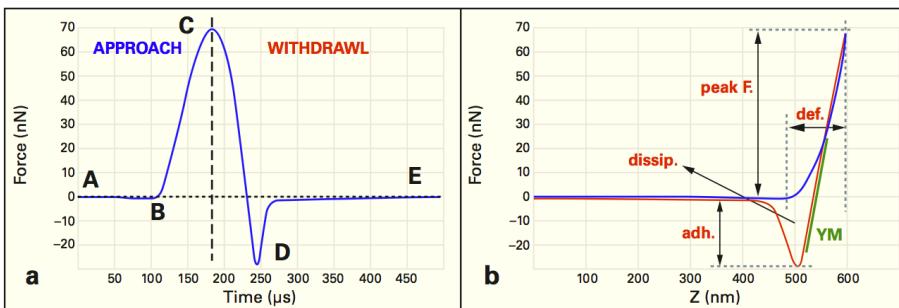
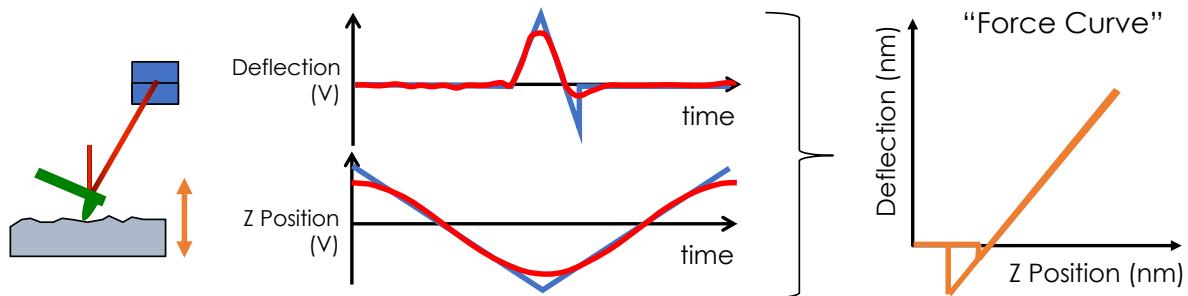
$$I_\varepsilon(\varphi) = \dots$$

Fd - Indentation

- Peak Force Quantitative NanoMechanical (QNM)

[www.bruker-axs.com]

- ↳ force curve recording at some kHz with sinusoidal displacement



Calibration!

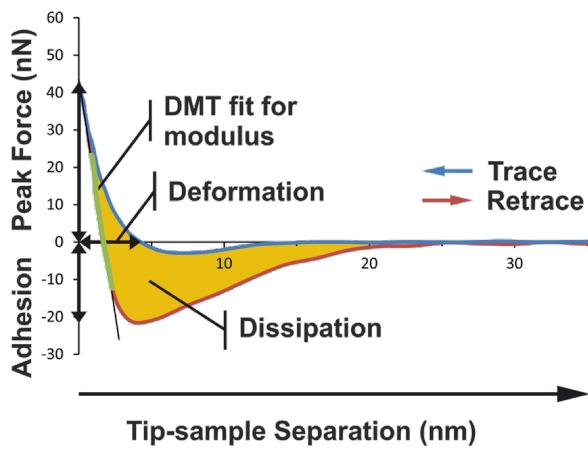
DMT modulus
Dissipation (hysteresis loop)
Adhesion force

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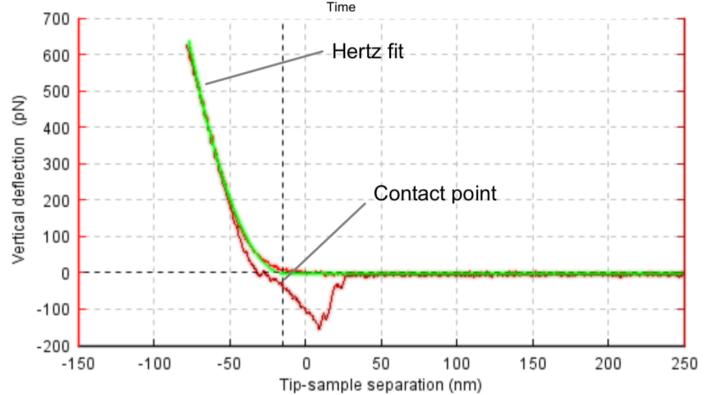
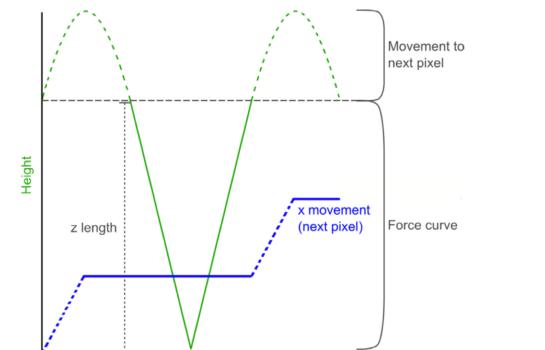
$$I_\varepsilon(\varphi) = \dots$$

Fd - Indentation

- Peak Force QNM (Bruker) vs. QI (JPK)



[Bruker Appl Note]

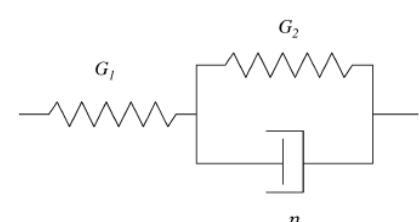
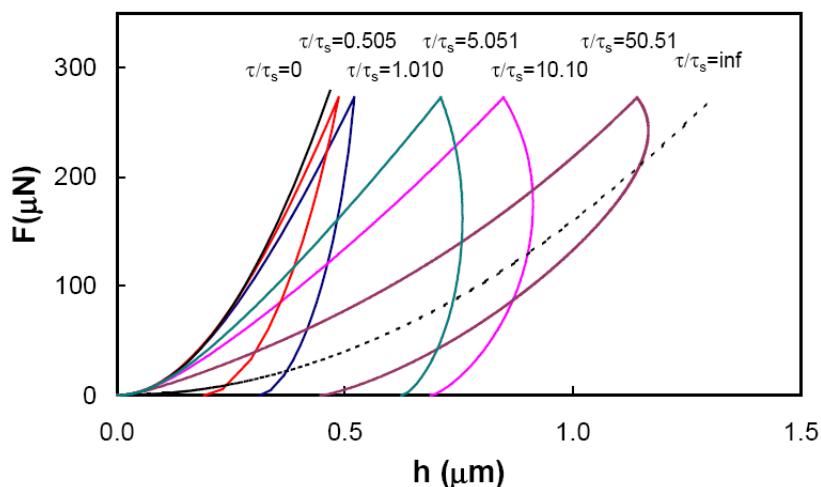


$$I_\varepsilon(\varphi) = \dots$$

Fd - Indentation

- Viscoelastic properties?

- Unloading curve of a viscoelastic material
[Cheng and Cheng, *Mat. Sci. Eng. R*, 2004]



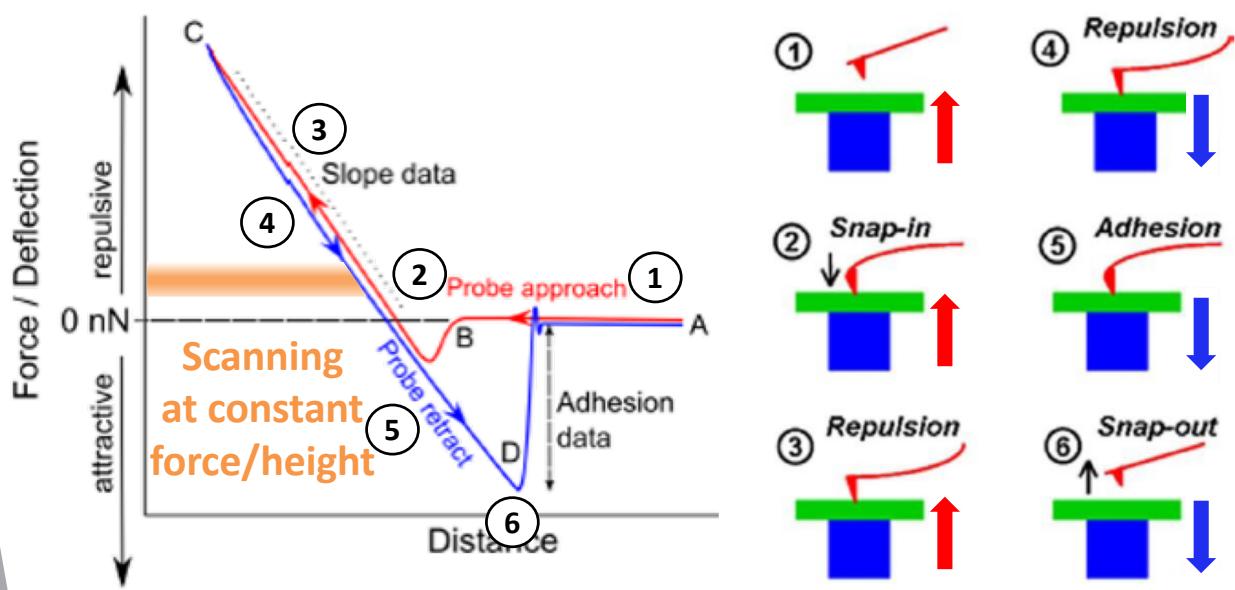
$$G_1 = 234 \text{ MPa} \quad G_2 = 26 \text{ MPa} \quad t_s = 1 \text{ s} \quad K = 688 \text{ MPa}$$

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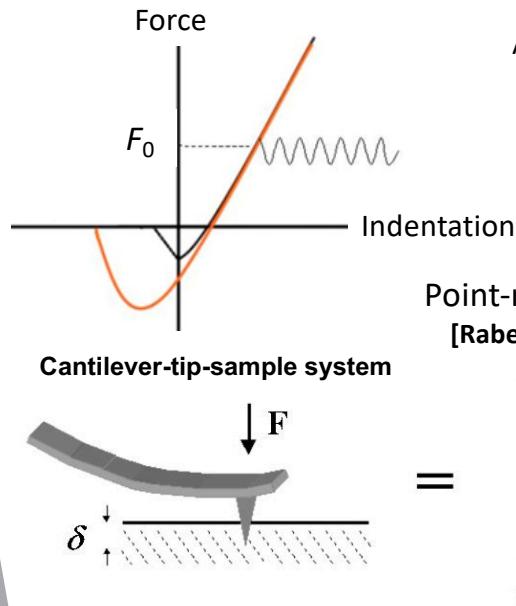
Contact Resonance-AFM (CR-AFM)



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Contact Resonance-AFM (CR-AFM)

IDEA: To probe the local elastic stiffness of the tip-sample system by means of cantilever's resonance frequency in contact mode at reduce applied force

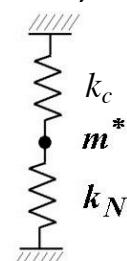


Applied force is modulated $F = F_0 + F_{\text{excitation}} \times \sin \omega t$

if $F_{\text{excitation}}$ is small \rightarrow LINEAR contact stiffness

if F_0 is small \rightarrow Good spatial resolution
+ Hertz theory validity

Point-mass model
[Rabe et al, 1996]



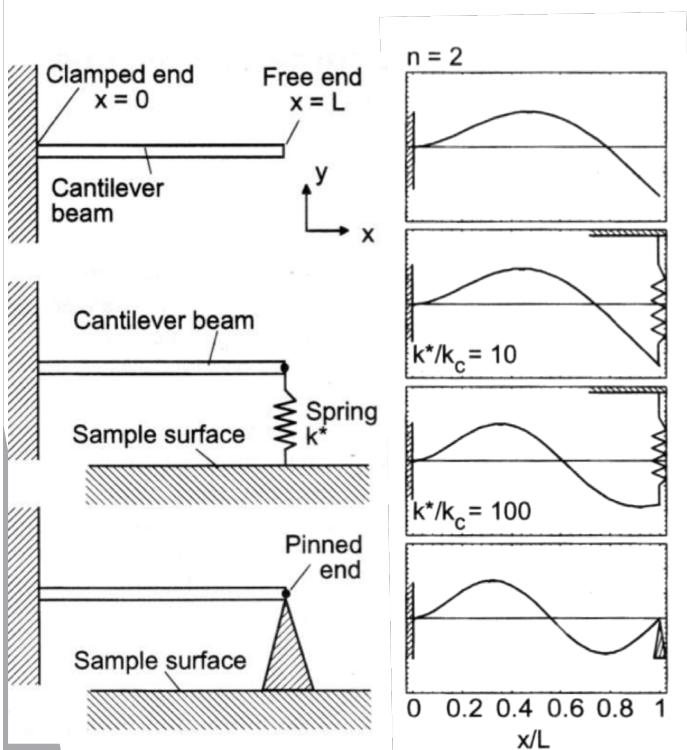
$$f_0 = \frac{1}{2\pi} \sqrt{\frac{k_c + k_N}{m^*}} \quad \text{with} \quad m^* = \frac{1}{4} m + m_{\text{tip}}$$

Amplitude of vibration and resonance frequency depend on the contact stiffness k_N ... but how?

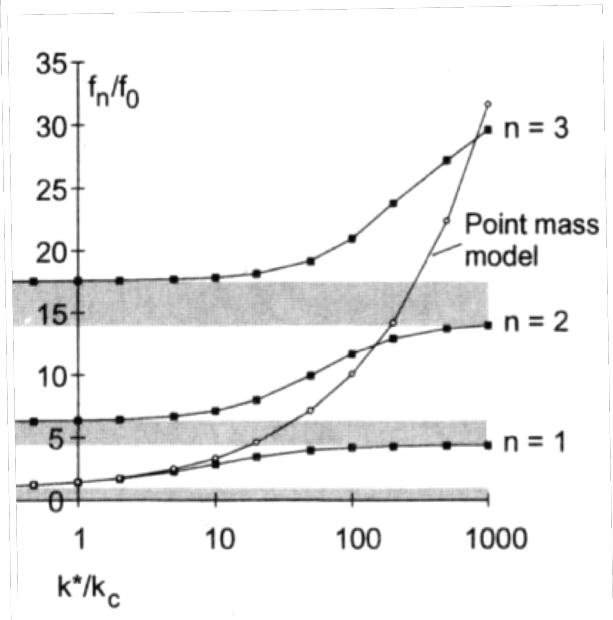
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Contact Resonance-AFM (CR-AFM)

Cantilever dynamic and response



[Rabe et al, 1996]



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CR-AFM - Cantilever dynamic

Sensitivity of the cantilever contact stiffness and considered mode

Example:

Probe: $k_c \approx 3 \text{ N/m}$,
 $R \approx 50 \text{ nm}$
 $F_0 \approx 200 \text{ nN}$

“Soft” sample
(Low T_g polymer)
 $k_N \approx 10 \text{ N/m}$

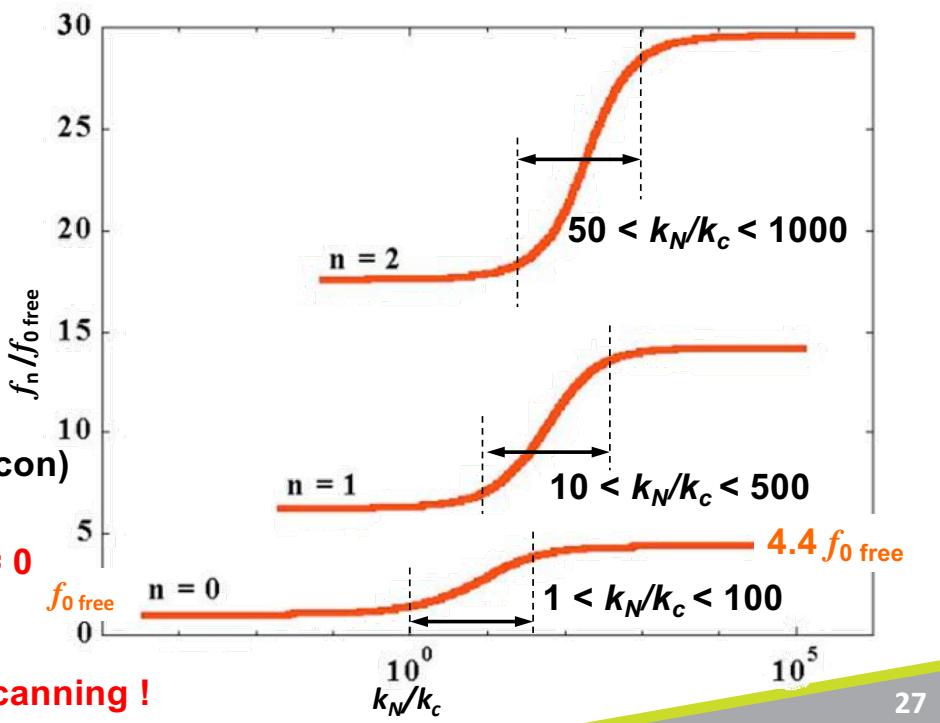
OK using $n = 0$

“Hard” sample (Silicon)
 $k_N \approx 1000 \text{ N/m}$

Not OK using $n = 0$

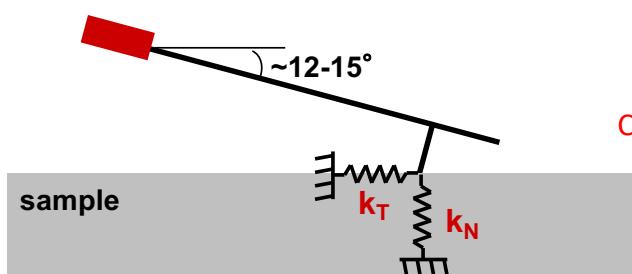
OK using $n > 0$

with low applied static force for scanning !



Cantilever dynamic: analytical model

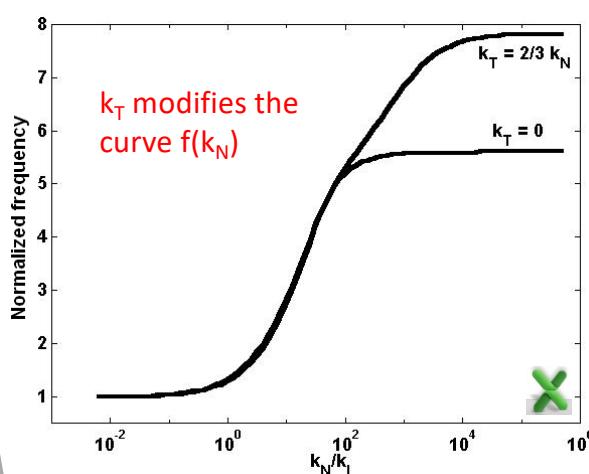
More realistic modelling: cantilever tilt



Normal and tangential components
of the tip displacement

CONTACT = normal spring k_N + tangential spring k_T

2 cases $\begin{cases} k_T \neq 0 + \text{adhesion} \rightarrow \text{Pinned contact} \\ k_T = 0 \text{ or no adh.} \rightarrow \text{Sliding contact} \end{cases}$



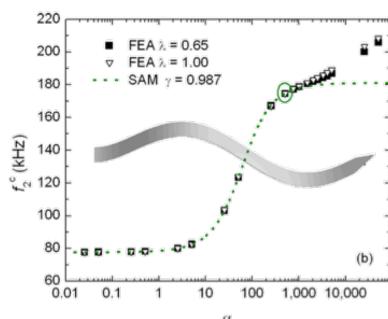
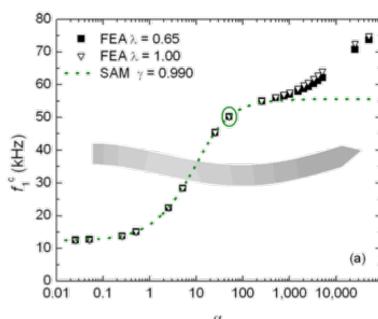
Problem: Analytical model do not allow to take into account the exact geometry of the cantilever (defaults, V-shaped...) and the specificities of the real excitation

$$I_\varepsilon(\varphi) =$$

$$\lim$$

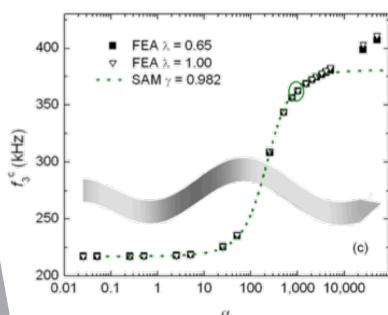
$$W(\cdot, F) = \infty$$

Cantilever dynamic: FE model...

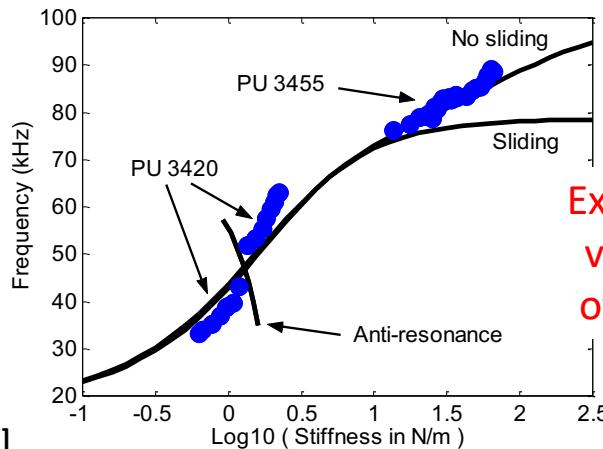


[Killgore and Hurley, 2012]

**Cantilever
and tip
calibration...!**



[Arinero and Levêque, 2003]



**Experimental
verification
of FE model**

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$$I_\varepsilon(\varphi) =$$

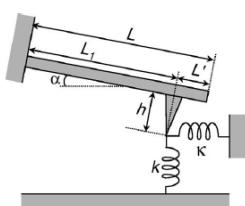
$$\lim$$

$$W(\cdot, F) = \infty$$

Cantilever dynamic: flexural and torsional resonance

Measurement of Poisson's ratio with Contact-resonance atomic force microscopy

[Hurley and Turner, 2007]



Young's modulus Shear modulus

$$k = 2aE^*$$

$$\kappa = 8G^*a$$

Contact area

$$M = E / (1 - \nu^2)$$

$$N = G / (2 - \nu)$$

Hertzian
Contact $m=3/2$
Flat punch $m=1$

$$E_s^* = E_{\text{ref}}^* \left(\frac{k_s}{k_{\text{ref}}} \right)^m \quad G_s^* = G_{\text{ref}}^* \left(\frac{\kappa_s}{\kappa_{\text{ref}}} \right) \left(\frac{k_s}{k_{\text{ref}}} \right)^{m-1}$$

**k and K provided by
flexural and torsional
resonance respectively**

$$\frac{1}{E_s^*} = \frac{1}{M_{\text{tip}}} + \frac{1}{M_s}$$

$$\frac{1}{G_s^*} = \frac{1}{N_{\text{tip}}} + \frac{1}{N_s}$$

Reference sample

Material	Source	M	N	$\nu = \frac{M-4N}{M-2N}$	$G = N(2-\nu)$	$E = M(1-\nu^2)$
SiO ₂	Literature	74.9	17.0	0.171	31.1	72.7
Glass	Literature	84.7	18.7	0.206	33.6	81.1
	Expt. m=1	81±5	18±2	0.21±0.11	32±5	76±6
	Expt. m=3/2	85±8	19±3	0.17±0.16	35±8	79±10

“Unknown” material

$$\nu = \frac{M - 4N}{M - 2N}$$

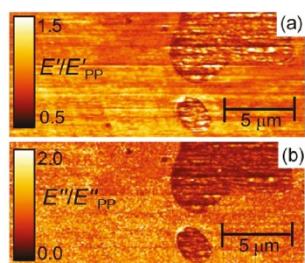
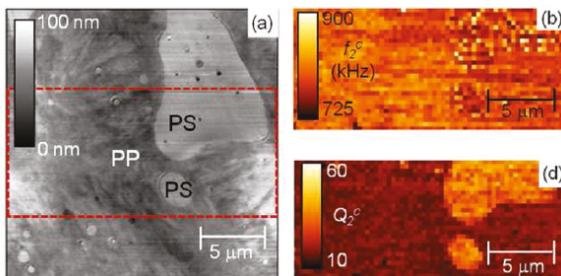
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Cantilever dynamic: effect of scanning velocity

Polystyrene polypropylene blend

[Killgore et al, Langmuir, 27, 13983, 2011]

PS regions: $f_2 = 792.1 \pm 31.7$ kHz, $Q_2 = 37.3 \pm 5$
PP regions: $f_2 = 801.7 \pm 17.4$ kHz, $Q_2 = 18.4 \pm 2.7$

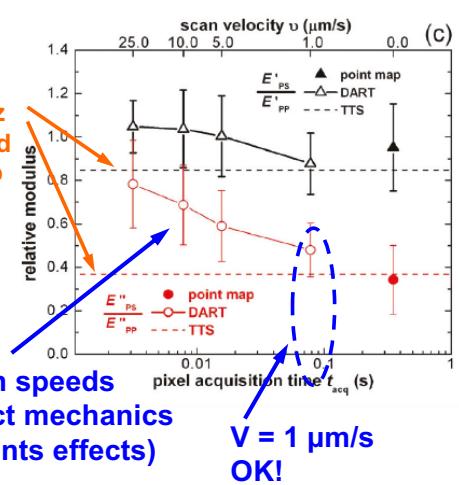


Tracking images

Cantilever modelling
+ contact mechanics model

+ Stick to sliding transition...

Expected at 1MHz
(DMA low freq and
low T + time temp
superposition)



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Sommaire

- Mécanique du contact et indentation
 - Contact élastique – Hertz
 - Nano-indentation – Oliver and Pharr
 - Domaines de validité, adhésion, anisotropie
- Courbe force-distance
 - Principe et prérequis
 - Traitement des courbes
- Contact résonant
 - Principe
 - Dynamique du levier et effet de la raideur latérale
- Préparation de la surface et calibrations

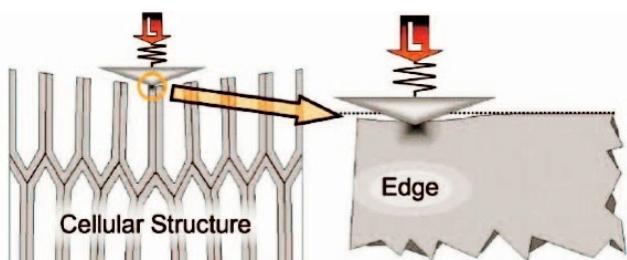
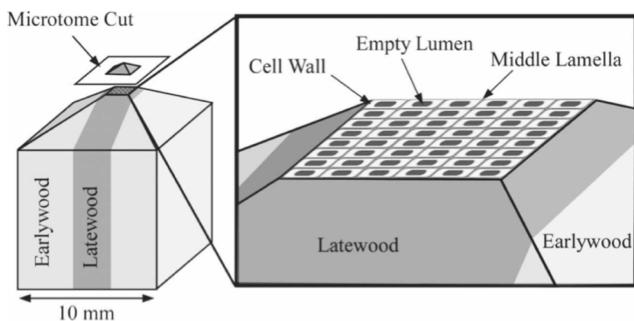
32

$$I_\varepsilon(\varphi) =$$

$$\lim_{\varepsilon \rightarrow 0} \frac{W(\cdot, F)}{\varepsilon} = \infty$$

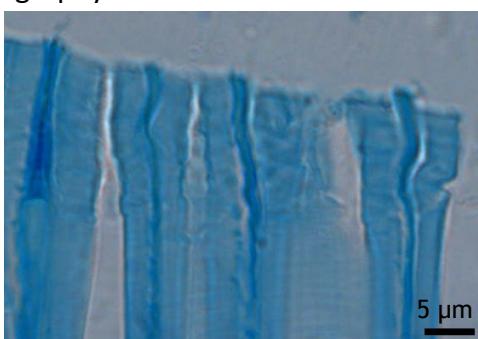
Sample preparation...

Without embedding in a resin: no sample modifications but \pm measurement artifacts



[Jakes et al, J. Mater. Res., 2008]

and topography...



[Clair, Gril et al, IAWA J., 2005]

\pm Dehydration in ethanol and embedding in resin (LR-White, SPURR, ...) or PEG

\pm no thermo-chemical modification of the cell wall (extractives...?)?
Resin penetration / inclusion time?
Cell wall water content?

! Microtome/Grinding/FIB...??!!

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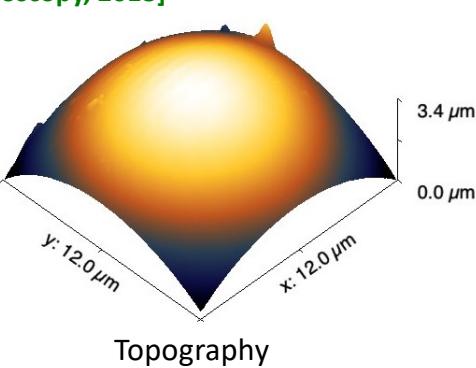
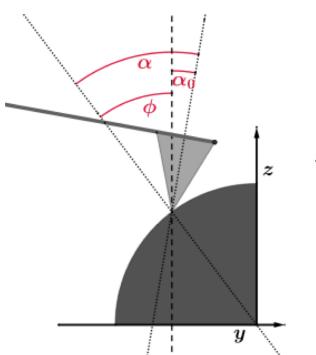
$$I_\varepsilon(\varphi) =$$

$$\lim_{\varepsilon \rightarrow 0} \frac{W(\cdot, F)}{\varepsilon} = \infty$$

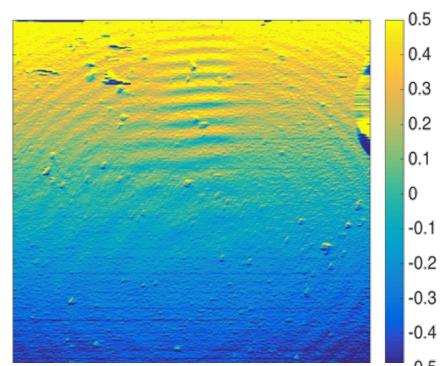
Sample surface effect

• Effect of sample local slope

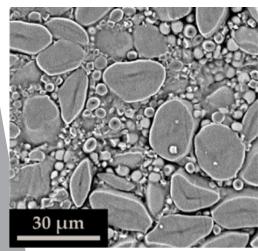
[Heinze et al, Ultramicroscopy, 2018]



Topography

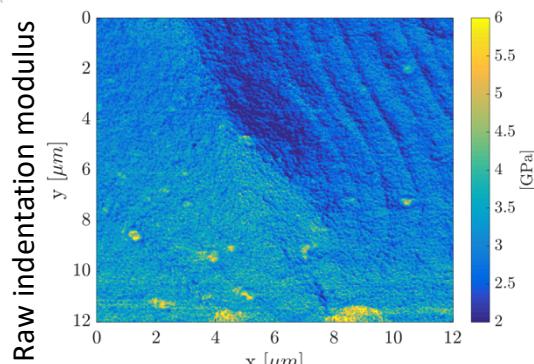


Local angle/cantilever ϕ ($^\circ$)



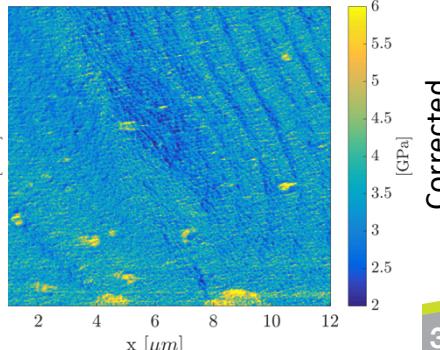
Starch granules

Raw indentation modulus



x [μm]

y [μm]



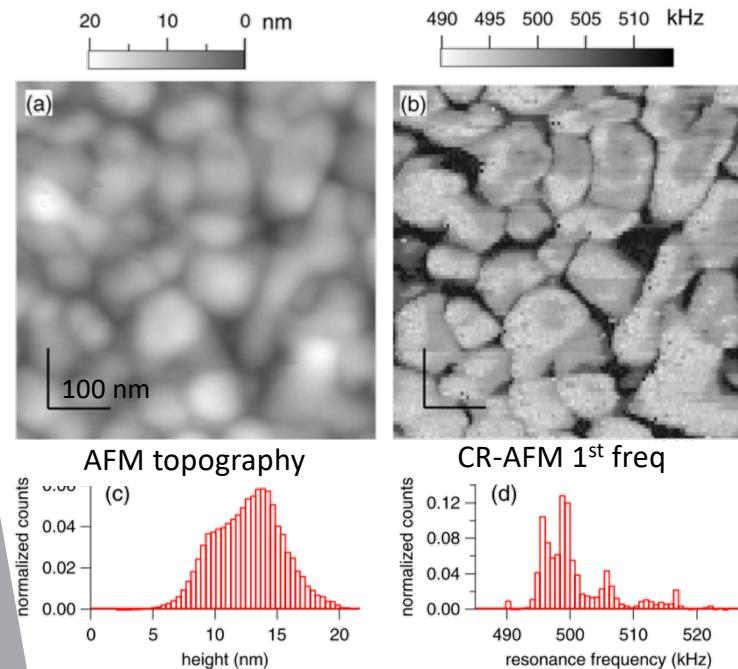
Corrected

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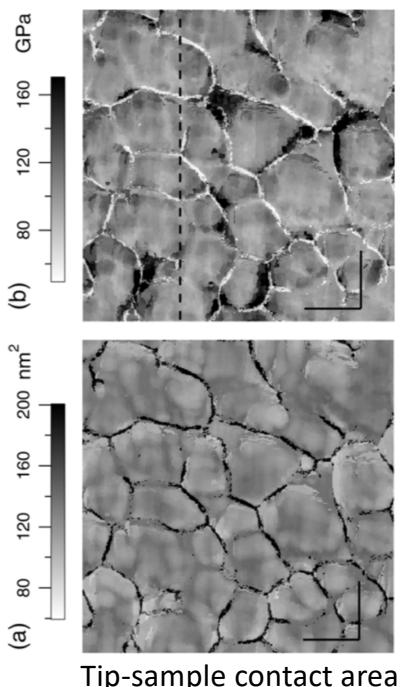
Sample surface effect

- Effect of sample roughness

Stan and Cook, Nanotechnology, 2008, 19, 235701



Corrected indentation modulus

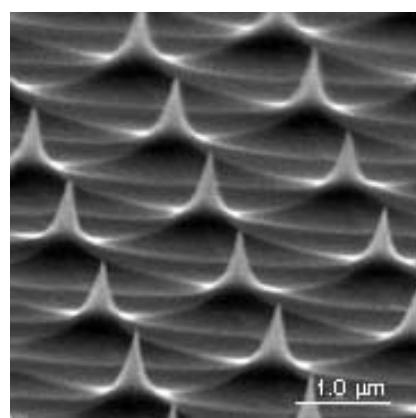
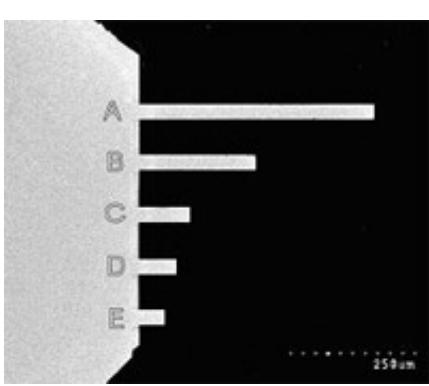


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Calibrations

- Probe calibrations

- Cantilever stiffness calibration methods: added mass, SEM imaging and mechanical beam model, Sader method, Thermal noise method, Reference cantilever array, ...



- Tip shape: SEM imaging, gratings (TipCheck, TGT), reference material(s)
- Tip position: SEM imaging, reference material(s)

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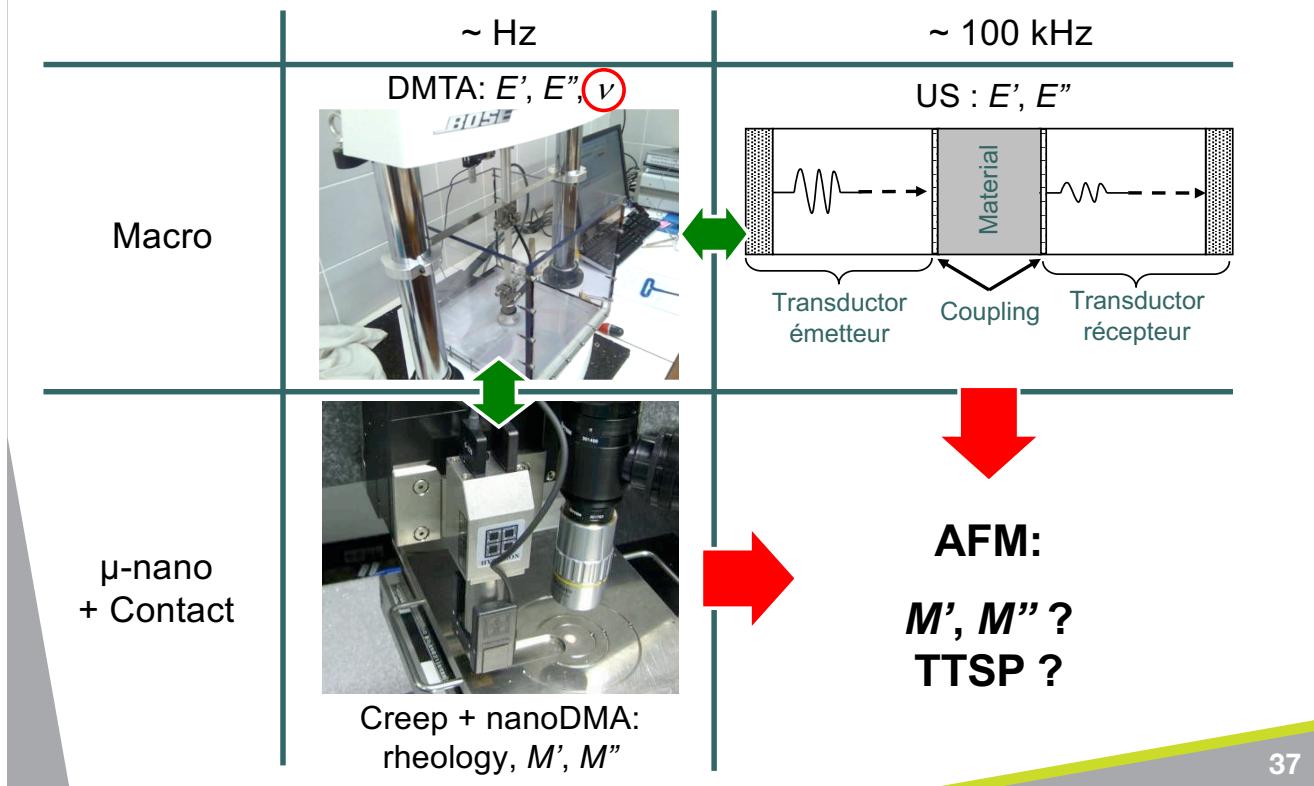
$$I_\varepsilon(\varphi) = \dots$$

$$\lim$$

$$W(\cdot, F) = \infty$$

Reference material samples

- Calibration?

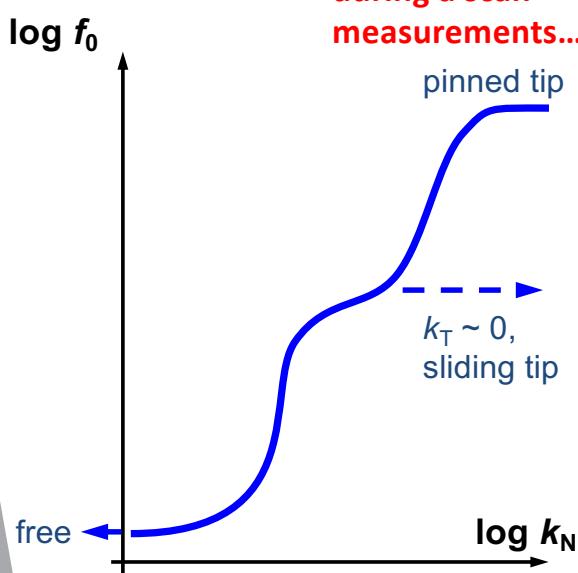


$$I_\varepsilon(\varphi) = \dots$$

Cantilever and tip calibration / reference samples

- CR-AFM

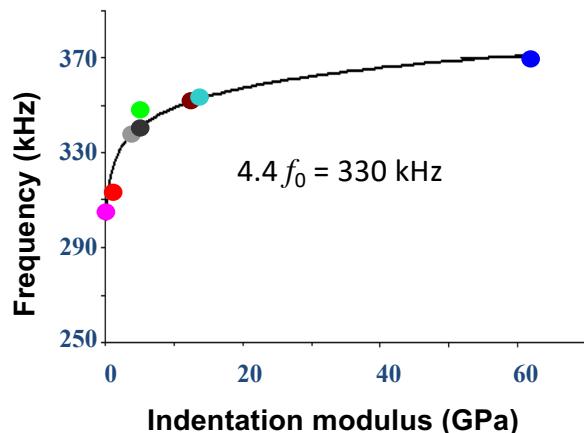
Static point or
during a scan
measurements...



Nanoworld ARROW FMR:
 $k_c \approx 2.8 \text{ N/m}$, $f_0 = 75 \text{ kHz}$, $R \approx 55 \text{ nm}$

Veeco Enviroscope: $F_0 \approx 180 \text{ nN}$

Single reference method??



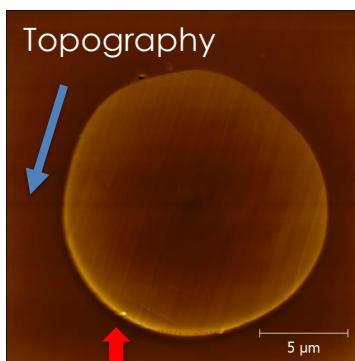
Material	M_N (GPa)	f_0 (kHz)
PU	0,14	305
PE	1,2	313
PMMA	4,9	350
glass	62	370
LR-White	5	338
S1/LM	5,5	341
S2	13	352
G	15	354

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Kevlar® Dupont™ K48 fibres

[Arnould et al, Ind. Crops Prod, 2017]

IRD



[Wollbrett-Blitz et al,
J. Polym. Sci., 2016]

Core:

$E_l = 84 \text{ GPa} / E_t = 3 \text{ GPa}$

Skin:

$E_l = 85 \text{ GPa} / E_t = 0,2 \text{ GPa}$

$G_{lt} = 1,8 \text{ GPa} / G_{tt} = 1,2 \text{ GPa}$

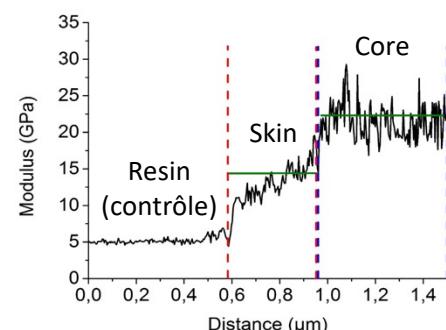
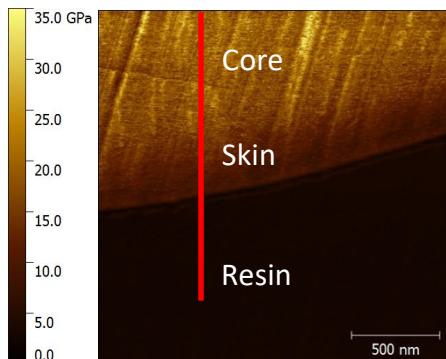
$\nu_{lt} = 0,6 / \nu_{tt} = 0,25$

$$M_{\text{core NI}} = 22,8 \pm 1,7 \text{ GPa}$$

(150 nm @ 1 $\mu\text{N/s}$ + 20 s + 10 $\mu\text{N/s}$)

$$M_{\text{core calc}} \approx 21 \text{ GPa}$$

$$M_{\text{skin calc}} \approx 17 \text{ GPa}$$



MultiMode 8, PF-QNM, Bruker RTESPA-525, 139 N/m, 32 nm (HOPG), 200 nN

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Conclusions – Questions ouvertes

- Respecter/vérifier les domaines de validité des modèles d'indentation suivant les conditions expérimentales (transition entre modèles ?)
- Attention au comportement anisotrope ($E \neq M$) surtout aux échelles nano
- Indentation non normale... raideur tangentiel en anisotrope ? Comment la mesurer ?
- Utilisation de la courbe d'approche ou de retrait ou ... ? Et effet de la viscosité ?
- Choix de la forme optimale de la pointe / rugosité ou hétérogénéité de la surface (+ tenue à l'usure)
- Choix de la raideur (et facteur de qualité) du levier / matériau à tester
- Effet de la topographie et de la profondeur de mesure par rapport aux effets de surface (liés à la préparation des échantillons + comportement matériaux)
- Mesure « intégrant » plus en profondeur ?
- Calibration des échantillons de référence en terme d'échelle, de fréquence (TTSP ?) et de mode de sollicitation ? Idem pour le matériau mesuré...
- Problème de la vitesse de sollicitation / comportement viscoélastique
- Mesure en milieu liquide, problème de l'adhésion (CR-AFM), mesure visco (Q)...

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